

Lecture 13: ***Lasers***

High Brightness Electron Injectors for Light Sources

January 14-18, 2007

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Outline

- Laser Parameters
 - Cathodes
 - Laser and Cathode
- Laser Components
 - Oscillator
 - Amplifier
 - Frequency Conversion
 - Transverse Pulse Shaping
 - Temporal Pulse Shaping
 - Transport Line
 - Diagnostics



Cathodes

Type	QE	Lifetime	Work Function	$\epsilon_{\text{thermal}}$
Metal	$\approx 10^{-4}$	Month	$\approx 4 \text{ eV}$	$>0.5 \mu\text{m/mm}$
Semi-conductor	$\approx 10^{-2}$	Hours	$\approx 2 \text{ eV}$	$>0.8 \mu\text{m/mm}$



Laser Cathode System

- Cathode choice determines laser parameters
- Laser choice determines operation of cathode



Parameters

- QE $5 \cdot 10^{-5}$ requires $100 \mu\text{J}$ of laser energy to generate 1 nC
- 100 Hz repetition rate requires 10 mW of power but 1 MHz requires 100 W
- 4.5 eV work function requires 275 nm photon but 2.2 eV work function requires 550 nm photons

$$QE = \frac{n_{\text{electrons}}}{n_{\text{photons}}}$$

$$Q = en_{\text{electrons}}$$

$$E_{\text{laser}} = \frac{hc}{\lambda} n_{\text{photons}} = \frac{hcQ}{\lambda eQE}$$

$$P_{\text{laser}} = RE_{\text{laser}} = \frac{hcQR}{\lambda eQE}$$

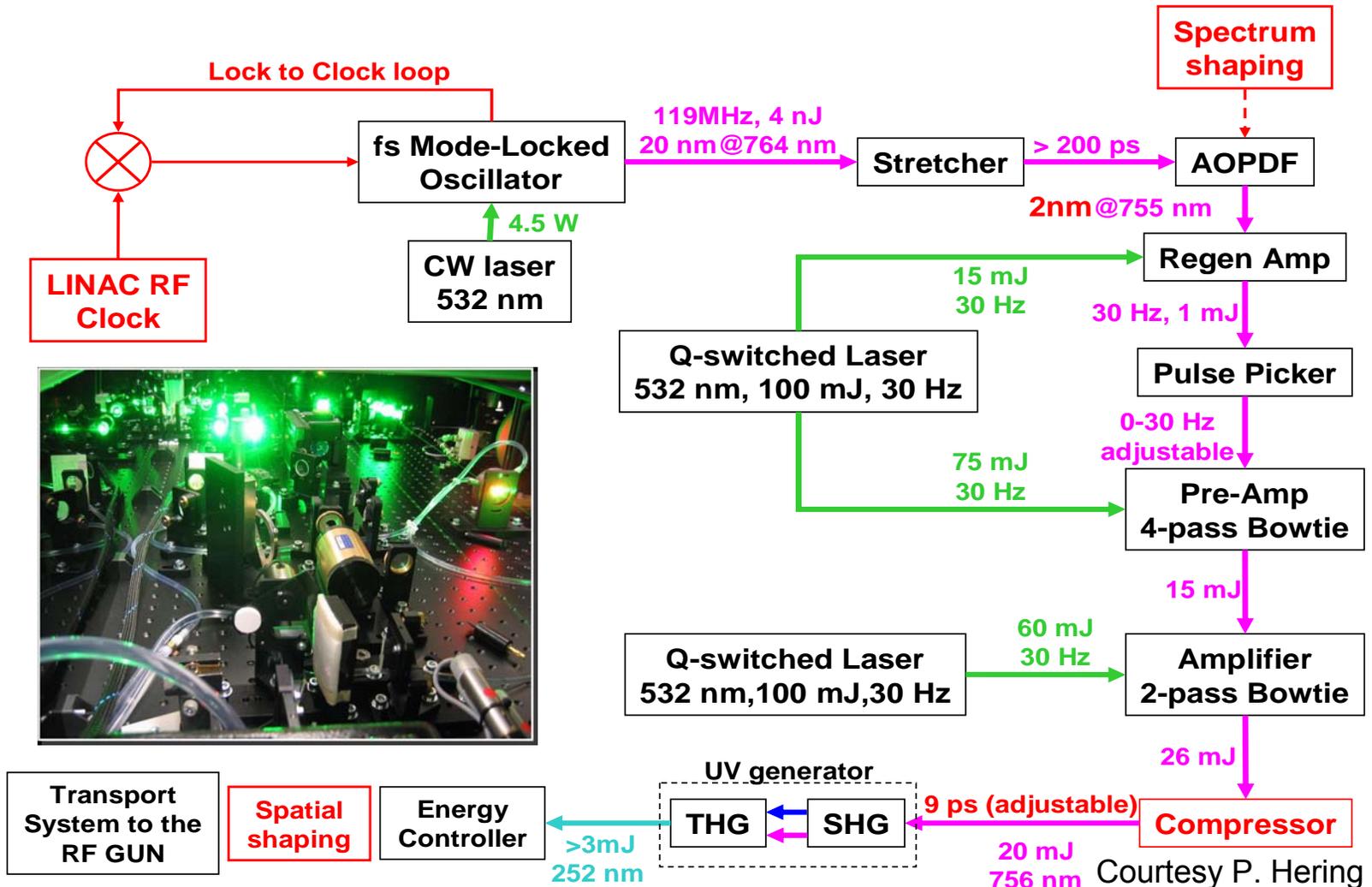


Specs at the Cathode

- Wavelength
- Energy
- Temporal Pulse Shape
- Beam Size
- Transverse Beam Shape
- Repetition Rate



LCLS Injector Drive Laser



Courtesy P. Hering



Oscillator

- Operates at sub-harmonic of RF frequency
 - Typical round trip time is 10 ns
 - ≈ 100 MHz pulse rate which is 28th sub-harmonic of S-band
- Phase lock laser to RF system
 - Require $< 1^\circ$ of jitter at RF frequency
 - Minimize jitter by locking harmonic rather than the laser fundamental frequency
- Pulse energy roughly 1 nJ
 - Requires significant amplification for injector application
- Oscillator must provide sufficient bandwidth for pulse shaping in later stages
 - Generally produce ≈ 100 fs pulse length



Amplifier

- Total gain required is approximately 7 orders of magnitude
- Use a regenerative amplifier, to amplify to mJ level and external amplifiers for final amplification
- Chirped Pulse Amplification (CPA)
 - Stretch pulse in time
 - Minimizes non-linear effects such as self focussing, self phase modulation
 - Allows increased amplification
 - Pulse is compressed after amplification
- Diode pumped amplifier minimize energy fluctuations
- Thermal effects limit rep rate and energy per pulse



Frequency Conversion

- Non-linear crystal with second order susceptibility
- Process commonly called Second Harmonic Generation (SHG)
- May require multiple stages to reach final photon energy
- Since process depends on E^2 or I , the final pulse length is often smaller than the input pulse length

$$P = \chi_1 E + \chi_2 E^2 + \chi_3 E^3 + \dots$$

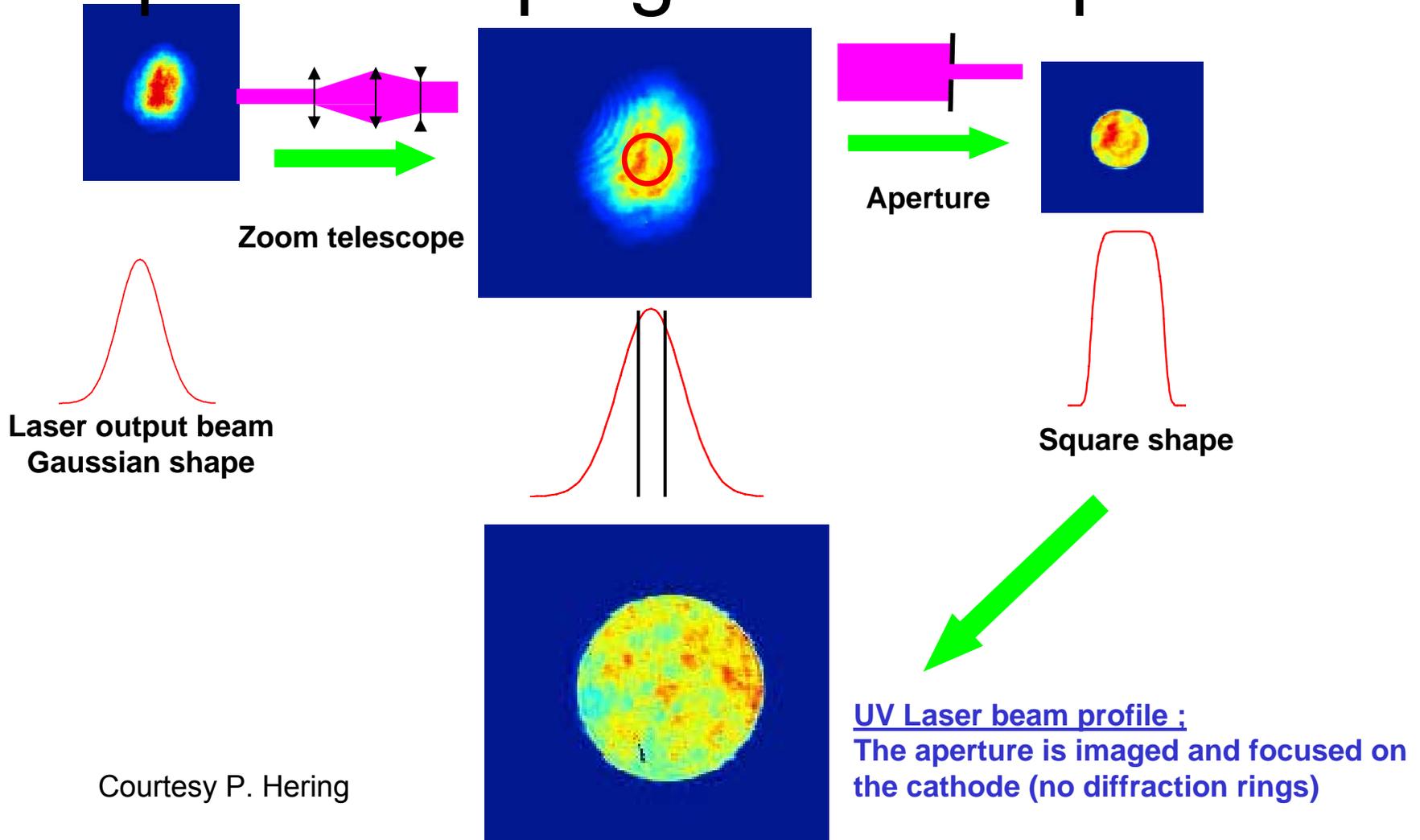


Spatial Shaping

- Transverse shape of the laser is reproduced on the electron beam assuming the QE is independent of position
- Methods
 - Aperture Clipping
 - Aspheric Lens
 - Adaptive Optics



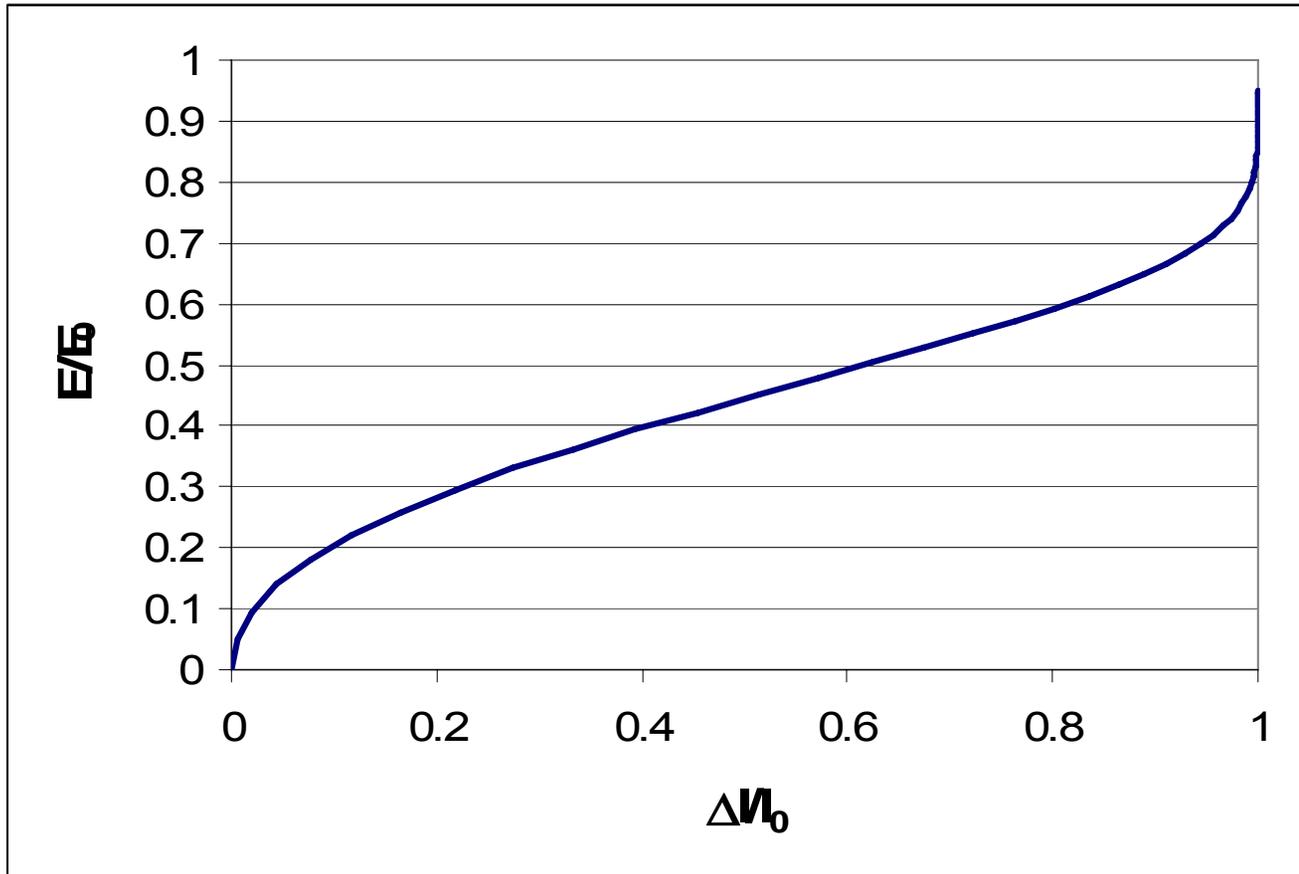
Spatial Shaping With an Aperture



Courtesy P. Hering

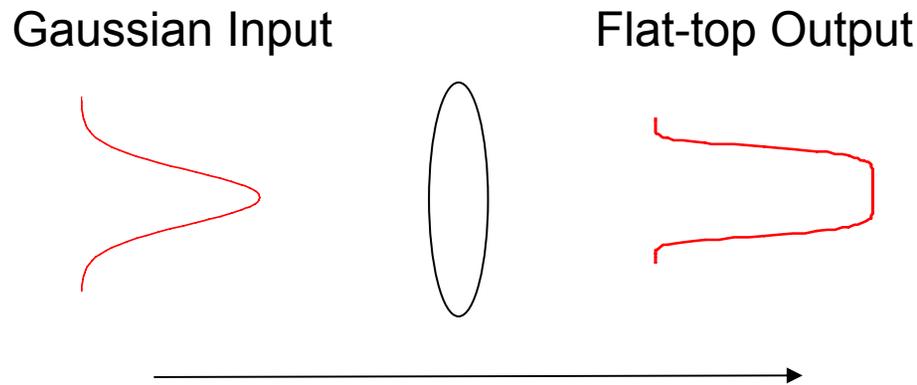


Energy Loss With Aperture Clipping



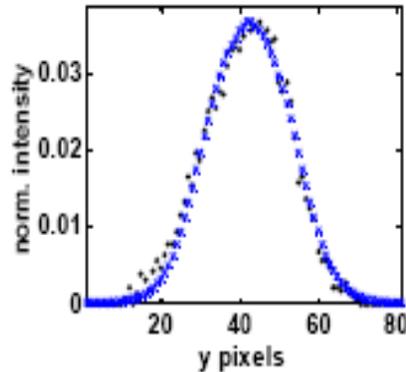
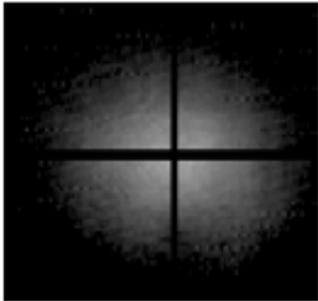
Aspheric Lens

- Lens shaped to produce flat top output for a Gaussian input with a specific beam size
- Transmission near 100%
- Developed by IBM for lithography application
- Now commercially available from Newport

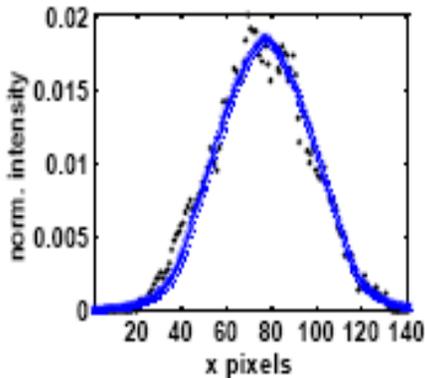
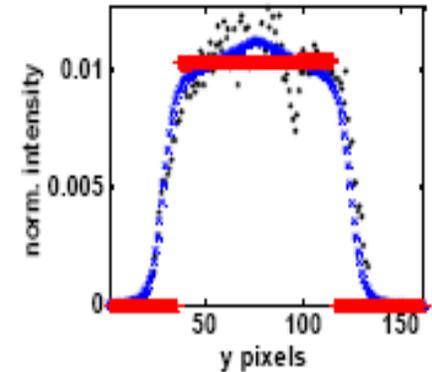
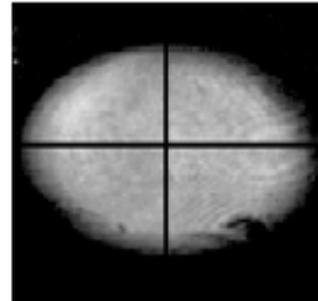


Aspheric Lens Measurement

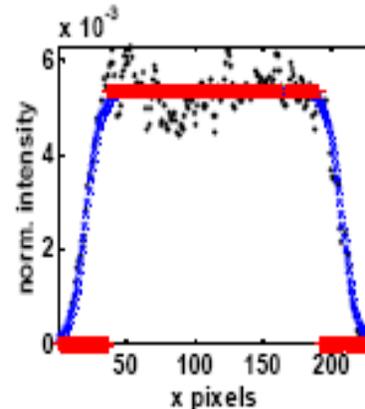
Image



Image



	x	y
centroid, um	2.71e+003	2.98e+003
1/e ² width, um	1.55e+003	1.71e+003
beta	4.41	3.85
F-D err	0.000134	0.000203



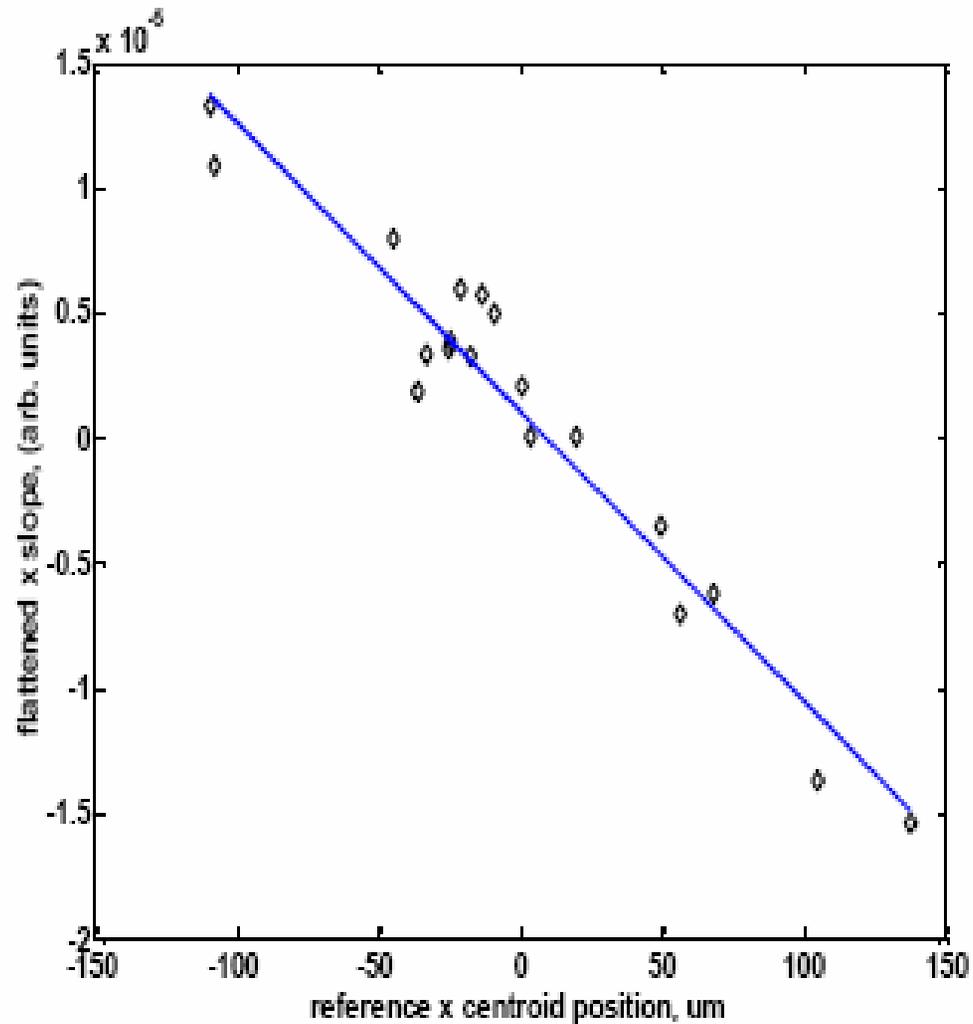
	x	y
centroid, um	4.01e+003	5.28e+003
FWHM, um	3.29e+003	3.03e+003
beta	18	14.2
F-D err	3.62e-005	0.000147
slope	6.77e-008	1.19e-006
lin. err	0.00544	0.0101
min/max	0.998	0.991

Input Gaussian

Output Flat-top



Effect of Input Position Jitter



Adaptive Optics

- Deformable mirror used to generate nearly arbitrary transverse pulse shape
- In principle could be combined with e-beam transverse shape measurement to compensate for QE spatial variations and generate a flat e-beam transverse shape



Dazzler

- Acousto-Optic Programmable Dispersive Filter (AOPDF)
- Birefringent TeO_2 Bragg diffracts different wavelengths at different depths
 - Optical path, or phase, is wavelength dependent
 - The phase delay of each wavelength is adjustable
 - Can generate approximate flat-top pulse

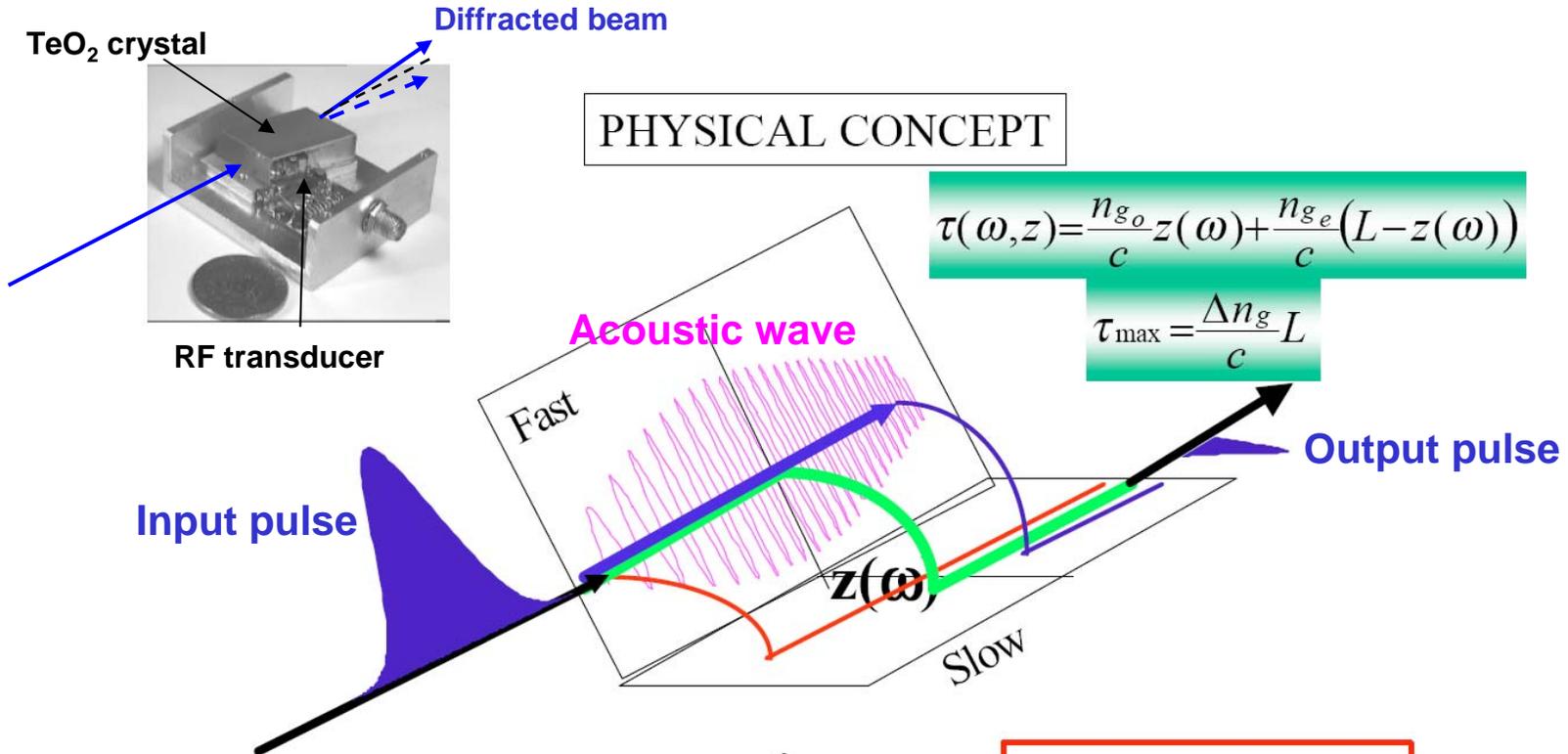


Temporal Pulse Shaping

- Dazzler (AOPDF)
- Frequency Domain
- Time Domain



Acousto-Optic Programmable Dispersive Filter Dazzler



PHYSICAL CONCEPT

$$\tau(\omega, z) = \frac{n_{g_o}}{c} z(\omega) + \frac{n_{g_e}}{c} (L - z(\omega))$$

$$\tau_{\max} = \frac{\Delta n_g}{c} L$$

$$E_{out}(t) \propto S(t/\alpha) \otimes E_{in}(t) \quad \text{où} \quad \alpha = \frac{f_{ac}}{f_{opt}} \approx 10^{-7} \Rightarrow E_{out}(\omega) \propto S(\alpha\omega) E_{in}(\omega)$$

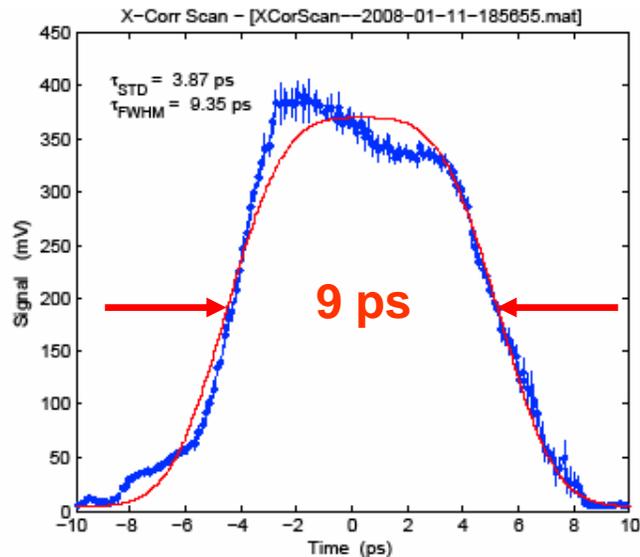
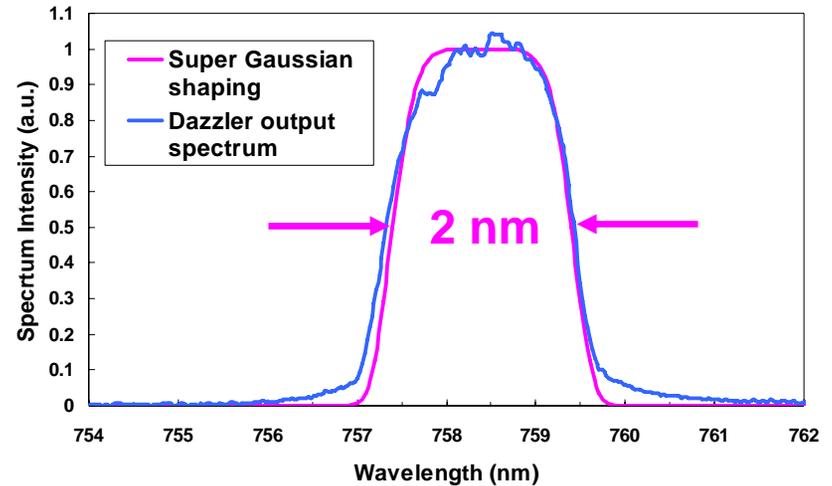
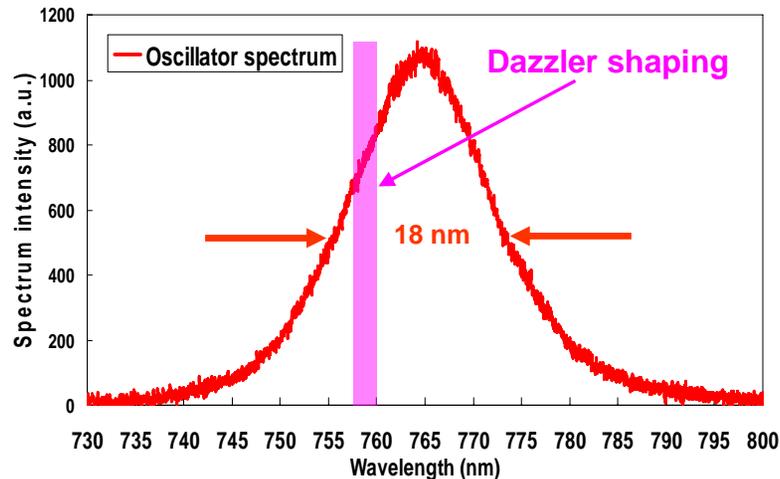
P. Tournois, Opt. Comm. **140**, 245 (1997)

F. Verluise, V. Laude, Z. Cheng, Ch. Spielmann et P. Tournois, Opt. Lett. **25**, 575 (2000)

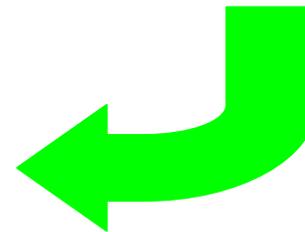
Courtesy P. Hering



Temporal Shaping with Dazzler



The time shape via the spectrum shape is fixed by the Dazzler

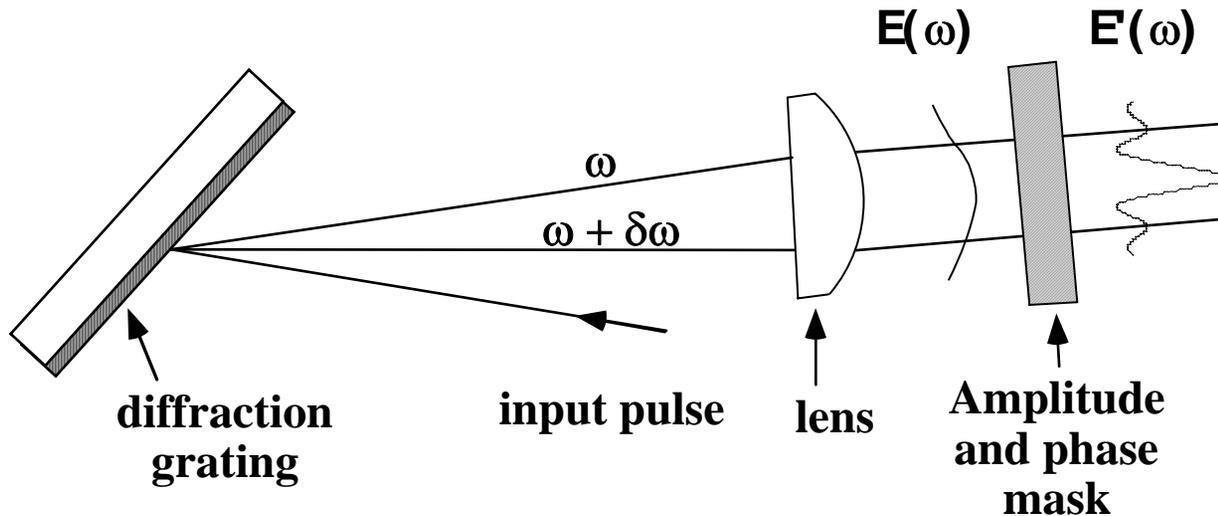


Courtesy P. Hering

Temporal profile obtained in the UV :
The pulse duration is fixed by the compressor



Frequency Domain Pulse Shaping



$$E'(\omega) = E(\omega)T(\omega) \quad I(t) = \left| \int_{-\infty}^{\infty} E'(\omega) e^{-j\omega t} d\omega \right|^2$$

Can generate nearly arbitrary pulse shapes limited by input bandwidth and available masks

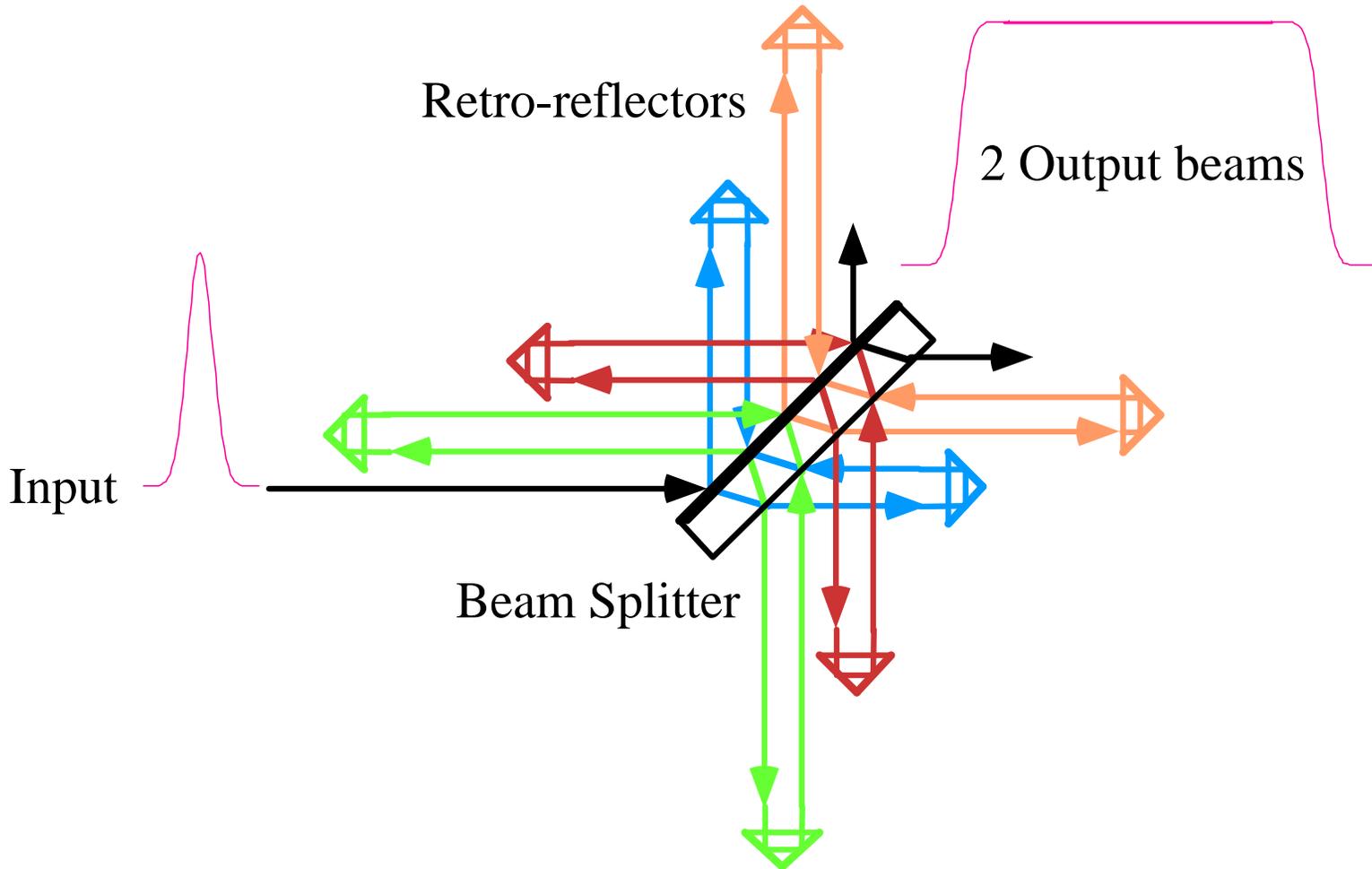


Time Domain Pulse Shaping

- Split beam into multiple pulses
- Adjust delay of each pulse and recombine
- Gaussian pulse with delay between pulses approximately equal to the rms width produce approximately flat-top pulse
- Interference between pulses problematic
 - Rotate polarization between pulses minimizes interference
 - Elliptical polarization requires normal incidence due to QE variation with polarisation



Time Domain Pulse Shaping



Transport System

- Typically on the order of 10 m between the laser room and the gun
- Transport system must maintain all laser parameters with minimal loss
- Typically relay image the desired plane in the laser room to the cathode
 - Maintains transverse beam shape
 - Minimizes positional jitter
- Some system use a hard aperture a few cm before the cathode to produce a final



Diagnostics

- Monitor Spectrum
- Pulse Length
 - Streak Camera
 - AutoCorrelator
 - Cross Correlator
- Pulse Shape
 - CCD camera at virtual camera location
- Energy per pulse



Losses

- Transmission After Amplifier
 - Compression – 50%
 - Frequency Conversion – 10%
 - Temporal Pulse Shaping – 50%
 - Transverse Pulse Shaping – 25%
 - Transport – 50%
 - Total Transmission – 0.3%
- For 100 μJ at cathode requires 30 mJ from the amplifier



Summary

- Laser System very complex and usually requires dedicated operators
- Laser specs highly dependent on choice of cathode
- Laser is a significant fraction of the cost of the injector

